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 / Ruth Montalvo Date: 12/22/05

Customer No. 026418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney's Docket No.: JG-SU-5222/500577.20072
 U.S. Application No.:
 International Application No.: PCT/JP2004/016001
 International Filing Date: OCTOBER 28, 2004 28 OCTOBER 2004
 Priority Date Claimed: DECEMBER 01, 2003 01 DECEMBER 2003
 Title of Invention: MANUFACTURING METHOD OF SILICON WAFER
 Applicant(s) for (DO/EO/US): Sakae KOYATA and Kazushige TAKAISHI

Mail Stop PCT
 Commissioner For Patents
 P.O. Box 1450
 Alexandria, VA 22313-450

INFORMATION DISCLOSURE STATEMENT

S I R:

Applicant herewith submits together with the simultaneously filed National Phase application of PCT/JP2004/016001, a copy of the International Search Report (PCT/ISA/210) dated February 15, 2005, citing some of the following references:

	Document Number	Date	Name and/or Country	English Translation and/or Equivalent
AA	6,099,748	08/08/2000	Netsu, et al.	
AL	60-197367	10/05/1985	Japan	Abstract only
AM	07-045564	02/14/1995	Japan	Abstract only
AN	11-171693	06/29/1999	Japan	Abstract only
AO	11-233485	08/27/1999	Japan	Abstract only
AP	2001-223187	08/17/2001	Japan	Abstract only
AQ	2003-100701	04/04/2003	Japan	Abstract only
AR	2003-203890	08/17/2003	Japan	Abstract only

Accompanying this Information Disclosure Statement and form PTO-1449 are copies of the documents including English Abstract and US equivalent. Document A9 is mentioned on page 3 of the substitute specification.

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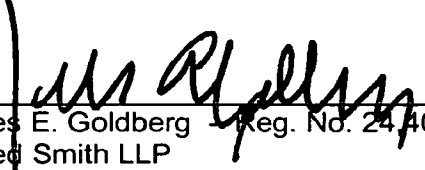
The USPTO waived the requirement under 37 C.F.R. §1.98(a)(2)(i) for submitting copies of US patents and US patent application publications in all U.S. applications filed after June 30, 2003. First pages of US documents only.

This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

Respectfully submitted,

JEG:ram
08/10/05
Tel. (212) 521-5400
Enclosures:

Search Report (PCT/ISA/210);
PTO-1449
1 first page US Patents
7 foreign documents
7 English Abstracts



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LIST OF PRIOR ART CITED BY APPLICANT
(Filed on December 22, 2005)

Docket No. **JG-SU-5222/500577.20072**Applicant(s): **Sakae KOYATA and Kazushige TAKAISHI**

Application No. (Int'l Appln No. PCT/JP2004/016001 28OCT04) Group:

Filed: Examiner:

U.S. PATENT DOCUMENTS

Exam. Init		Document Number	Date	Name	Class	Sub-Class	Filing Date Appropriate
/KC/	AA	6,099,748	08/08/2000	Netsu, et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	CLASS	Sub-Class	Translation	
							YES	NO
/KC/	AL	60-197367	10/05/1985	Japan			Abstract only	
/KC/	AM	07-045564	02/14/1995	Japan			Abstract only	
/KC/	AN	11-171693	06/29/1999	Japan			Abstract only	
/KC/	AO	11-233485	08/27/1999	Japan			Abstract only	
/KC/	AP	2001-223187	08/17/2001	Japan			Abstract only	
/KC/	AQ	2003-100701	04/04/2003	Japan			Abstract only	
/KC/	AR	2003-203890	08/17/2003	Japan			Abstract only	
	AS							
	AT							

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AX	
	AY	
	AZ	

Examiner: /Kin Chan Chen/

Date: 01/24/2009

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.